

2" Sphere, General Purpose Integrating Sphere System



General Purpose Integrating Spheres

Stock **#58-584** **2 In Stock**

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1

+

C\$3,535⁰⁰

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Volume Pricing	
Qty 1-9	C\$3,535.00 each
Qty 10-24	C\$3,181.50 each
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Product Downloads

General

Note:

Included Accessories:
SMA Adapters: [#89-643](#) (x2)
Port Plugs: [#89-644](#) (x1) and [#89-645](#) (x1)

Physical & Mechanical Properties

Diameter (inches):

2

Diameter of 0° Port (inches):

1.00

0.50	Diameter of Port 2 (inches):
0.50	Diameter of Port 3 (inches):
1.00 & 0.50	Diameter of Port Plugs (inches):
0.50	Diameter of SMA Adapter (inches):
2.61 x 2.61 x 2.61 (Cubic Outer Shape)	Dimensions (inches):

Optical Properties	
Spectralon®	Coating:
8 J/cm²	Damage Threshold, By Design: ☐

Threading & Mounting	
¼-20	Mounting Threads:

Environmental & Durability Factors	
Up to 350°C	Thermal Stability:

Regulatory Compliance	
Compliant	RoHS 2015:
Compliant	Reach 209:
View	Certificate of Conformance:

Product Details

- Ideal for Measuring Light Sources
- Can be Upgraded to Calibrate Sensors and Test Lenses
- Designed for Simple System Integration

General Purpose Integrating Sphere Systems are designed to spatially integrate radiant flux in order to measure optical radiation. The spheres can be coupled with a sensor to create radiometers, photometers, or spectroradiometers in order to measure the total geometric flux emanating from a light source or the flux density of an illuminated area. Additionally, these sphere systems can be used to measure the output of high power lasers and laser diodes or to measure the reflectance and transmittance of materials.

A variety of accessories are available for modifying or upgrading the performance of the systems, including port plugs, port reducers, and uniform source lamps. Uniform source lamps are ideal for many irradiance applications, such as characterizing the responsivity, linearity, photo response non-uniformity, and dynamic range of focal-plan arrays. Additionally, these sources can be used for evenly illuminating test targets for evaluating the CTF of optical systems or imaging lenses, and for measuring cosine⁴ irradiance falloff or other variations in irradiance within optical systems caused by optical aberrations.